WHAT IS CLAIMED IS:

1. A substrate processing apparatus for processing a substrate, the apparatus comprising:

a stage configured to hold and move a substrate to be processed;

a conveying unit configured to hold and convey the substrate to be processed between the conveying unit and the stage;

an accumulation unit configured to accumulate control information concerning the stage and the conveying unit generated as a result of previous processing of a substrate that has already been processed; and

a determination unit configured to determine a conveying procedure for conveying the substrate to be processed between the stage and the conveying unit by selecting one of a plurality of conveying procedures which can be set for the stage and the conveying unit based on the control information accumulated in the accumulation unit.

2. The apparatus according to claim 1, further comprising a storage unit configured to store the plurality of conveying procedures,

wherein the determination unit determines a conveying procedure when conveying the substrate to be processed by selecting one of the plurality of conveying procedures stored in the storage unit based on the control information accumulated in the accumulation unit.

3. The apparatus according to claim 1, wherein the plurality of conveying procedures include a first conveying procedure and a second conveying procedure,

the first conveying procedure is a conveying procedure prioritizing productivity concerning conveyance of the substrate more than the

second conveying procedure, and

the second conveying procedure is a conveying procedure prioritizing stability concerning conveyance of the substrate more than the first conveying procedure.

4. The apparatus according to claim 3, wherein the first conveying procedure is a procedure in which the substrate is transferred from the conveying unit to the stage at a substrate loading position, from which the conveying unit and the stage are concurrently retracted, and

the second conveying procedure is a procedure in which the substrate is transferred from the conveying unit to the state at a substrate loading position, from which the conveying unit and the stage is retracted one after the other.

5. The apparatus according to claim 3, wherein the first conveying procedure is a procedure in which the substrate is transferred from the stage to the conveying unit at a substrate unloading position, to which the conveying unit and the stage are concurrently moved, and

the second conveying procedure is a procedure in which the substrate is transferred from the stage to the conveying unit at a substrate unloading position, to which the conveying unit and the stage are moved one after the other.

6. The apparatus according to claim 1, wherein the control information includes at least one of a holding force with which each of the stage and the conveying unit holds the substrate, a time required for each of the stage and the conveying unit to hold the substrate with a preset holding force, a

measurement value concerning alignment of the substrate which is performed when the substrate is conveyed between the stage and the conveying unit, and a number of errors in the alignment.

7. The apparatus according to claim 6, wherein the determination unit determines a conveying procedure for conveying the substrate to be processed between the stage and the conveying unit based on a result of comparing each of the holding force, the time, the measurement value, and the number of errors in the alignment and a threshold set for each of the holding force, the time, the measurement value, and the number of errors in the alignment.

8. The apparatus according to claim 7, further comprising a user interface configured to provide a user with a setting screen for setting the threshold.

9. The apparatus according to claim 1, wherein the substrate processing apparatus continuously processes a plurality of substrates included in the same lot, and

the determination unit determines a conveying procedure when conveying the substrate between the stage and the conveying unit while the plurality of substrates are continuously processed.

10. The apparatus according to claim 9, further comprising a notification unit configured to notify corresponding information when a conveying procedure is changed at a time of conveying the substrate between the stage and the conveying unit during continuous processing of the plurality of substrates and a measurement value concerning alignment of the substrate and the

number of errors in the alignment do not change before and after the change of the conveying procedure.

11. The apparatus according to claim 1, further comprising a projection optical system configured to project an image of a mask pattern on the substrate held by the stage.

12. An article manufacturing method comprising:

forming a pattern on a substrate by using a substrate processing apparatus defined in claim 1;

processing the substrate on which the pattern is formed in the forming; and

manufacturing an article from the processed substrate.

13. A substrate processing apparatus for processing a substrate, the apparatus comprising:

a stage configured to hold and move the substrate;

a conveying unit configured to hold and convey the substrate between conveying unit and the stage;

an accumulation unit configured to accumulate control information concerning the stage and the conveying unit which is generated by processing the substrate; and

a determination unit configured to determine a conveying procedure when conveying the substrate between the stage and the conveying unit by selecting one of a plurality of conveying procedures which can be set for the stage and the conveying unit based on control information accumulated in the accumulation unit,

wherein the control information includes at least one of a holding force with which each of the stage and the conveying unit holds the substrate, a time required for each of the stage and the conveying unit to hold the substrate with a preset holding force, a measurement value concerning alignment of the substrate which is performed when the substrate is conveyed between the stage and the conveying unit, and a number of errors in the alignment, and

the determination unit determines a conveying procedure when conveying the substrate between the stage and the conveying unit based on a result of comparing each of the holding force, the time, the measurement value, and the number of errors in the alignment and a threshold set for each of the holding force, the time, the measurement value, and the number of errors in the alignment.

14. The apparatus according to claim 13, further comprising a user interface configured to provide a user with a setting screen for setting the threshold.

15. An article manufacturing method comprising:

forming a pattern on a substrate by using a substrate processing apparatus defined in claim 13;

processing the substrate on which the pattern is formed in the forming; and

manufacturing an article from the processed substrate.